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Client Reference: P-1795.000-US



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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
BANINE ET AL.

Confirmation Number: 2813

Application No.: 10/748,851

Group Art Unit: 2851

Filed: December 31, 2003

Examiner: Della J. Rutledge

Title: LITHOGRAPHIC APPARATUS HAVING A DEBRIS-MITIGATION SYSTEM, A SOURCE FOR PRODUCING EUV RADIATION HAVING A DEBRIS MITIGATION SYSTEM AND A METHOD FOR MITIGATING DEBRIS

AMENDMENT UNDER 37 C.F.R. §1.312

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Sir:

In response to the Notice of Drawing Inconsistency with Specification mailed April 23, 2007, please amend the above-identified application as follows: